

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Young Hoon PARK, et al.)
Serial No.: 10/511,883) Group Art Unit: 1763
Filed: October 19, 2004)
For: APPARATUS AND METHOD FOR) Examiner:
DEPOSITING THIN FILM ON WAFER) NG, James Wai Heung
USING REMOTE PLASMA)

REPLY TO FINAL OFFICE ACTION UNDER 37 CFR 1.114
WITH REQUEST FOR CONTINUED EXAMINATION

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed September 11, 2007, Applicants request reconsideration in view of the following amendments and remarks for entry in the above-identified application.

Amendments to the Claims begin on page 2 of this paper; and

Remarks begin on page 7 of this paper.